

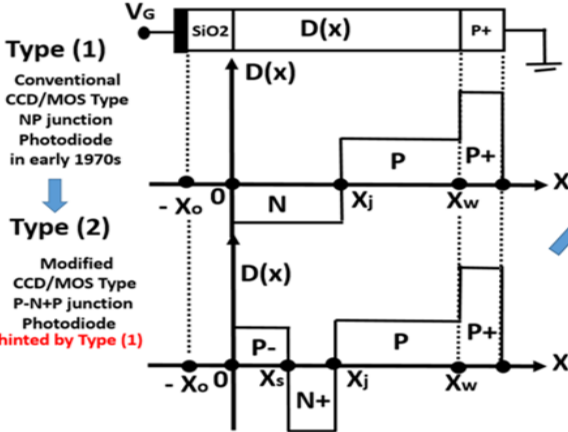
**Origin of 1975 Pinned Photodiode Concept  
was hinted by CCD/MOS type Buried Photodiode**

See JPA 1975-127646, JPA 1975-127647 and JPA 1975-134985

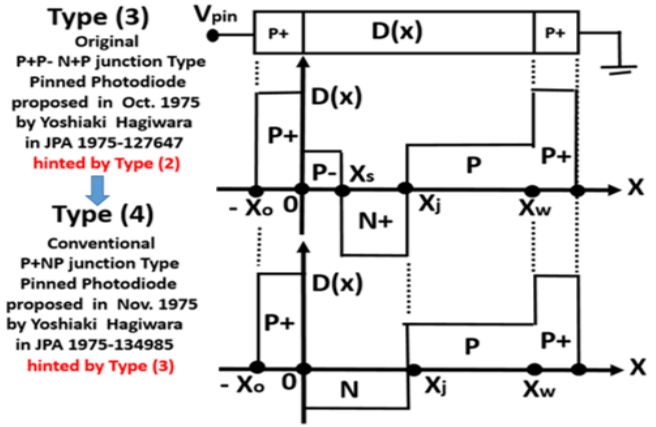
by Yoshiaki Hagiwara in 1975

Numerical Computation of Potential  $V(x)$  of Arbitrary Doping Profile  $D(x)$  from  $x = 0$  to  $x = X_w$  with the given boundary condition  $V(x) = V_s$  and  $dV(x)/dx = E_s$  at  $x = 0$ .  
Find the proper value of  $V(x) = V_s$  so that we have  $V(x) = V_w$  and  $dV(x)/dx = E_w$  at  $x = X_w$ .

**Conventional CCD/MOS type Photodiode**

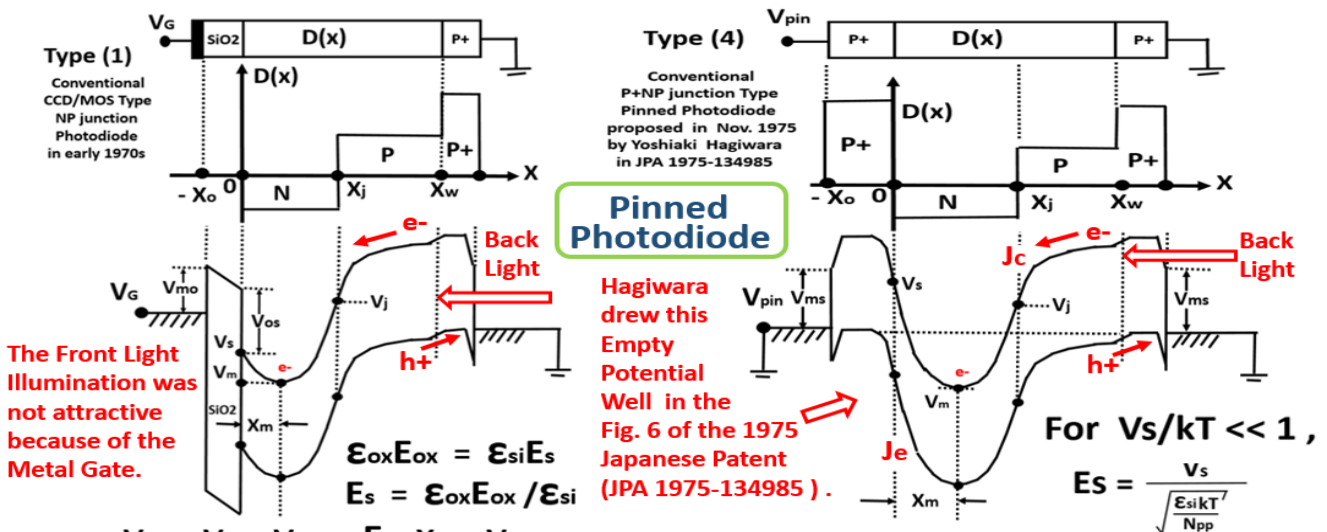


**Pinned Photodiode proposed in 1975**



<p align="center">For <math>x &lt; 0</math> in Type(1) and Type(2)</p> <p align="center" style="border: 1px solid black; padding: 2px;"><math>\frac{d^2V(x)}{dx^2} = 0</math></p> <p align="center">gives at <math>x = 0</math></p> <p align="center" style="border: 1px solid black; padding: 2px;"><math>E_s = C_{ox} (V_s - V_G + V_{mo} - V_{os}) / \epsilon_{si}</math></p>	<p align="center">For <math>x &lt; 0</math> in Type(3) and Type(4)</p> <p align="center" style="border: 1px solid black; padding: 2px;"><math>\epsilon_{si} \frac{d^2V(x)}{dx^2} = N_{pp} - N_{pp} \exp( (V_{pin} - V(x)) / kT )</math></p> <p align="center">gives at <math>x = 0</math></p> <p align="center" style="border: 1px solid black; padding: 2px;"><math>E_s = \sqrt{\frac{2 N_{pp} kT}{\epsilon_{si}} \left\{ \left( \frac{V_s}{kT} \right) - 1 + \exp \left( - \frac{V_s}{kT} \right) \right\}}</math></p>
<p align="center">For <math>0 &lt; x &lt; X_w</math> in all types (1) thru (4)</p> <p align="center" style="border: 1px solid black; padding: 2px;"><math>\epsilon_{si} \frac{d^2V(x)}{dx^2} = D(x) - N_{pp} \exp( - V(x) / kT )</math></p> <p align="center">needs to be solved numerically for any arbitrary doping function <math>D(x)</math>.</p>	<p align="center">For <math>X_w &lt; x</math> in all types (1) thru (4)</p> <p align="center" style="border: 1px solid black; padding: 2px;"><math>\epsilon_{si} \frac{d^2V(x)}{dx^2} = N_{pp} - N_{pp} \exp( - V(x) / kT )</math></p> <p align="center">gives at <math>x = X_w</math></p> <p align="center" style="border: 1px solid black; padding: 2px;"><math>E_w = - \sqrt{\frac{2 N_{pp} kT}{\epsilon_{si}} \left\{ \left( \frac{V_w}{kT} \right) - 1 + \exp \left( - \frac{V_w}{kT} \right) \right\}}</math></p>

The conventional Buried Channel CCD/MOS type photodiode has a very large surface electric field  $E_s$ .



$E_s = C_{ox} (V_s - V_G + V_{mo} - V_{os}) / \epsilon_{si}$

$E_s = \sqrt{\frac{2 N_{pp} kT}{\epsilon_{si}} \left\{ \left( \frac{V_s}{kT} \right) - 1 + \exp \left( - \frac{V_s}{kT} \right) \right\}}$

The surface electric field  $E_s$  of the P+NP junction type Pinned Photodiode is also very large which is worse since the surface electric field depends also on the surface P+ doping level  $N_{pp}$ .  
Type (2) and Type (3) modifications may help reducing the surface electric field  $E_s$ .